



Feature Selection for High-Dimensional Industrial Data

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Motivation

Problem statement

Quality control in semiconductor manufacturing plants (FABs) is becoming increasingly complex. Production problems causing low wafer yield are often hard to find.

Goals

- Identify problems during wafer production
- Give engineer problem insight
- Robust yield prediction



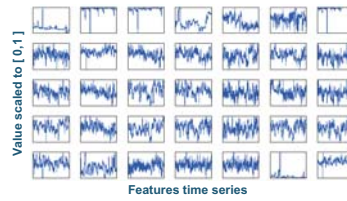
Methods

- Fuzzy ARTMAP neural network (FAM) [1]
- Feature selection [2] (feature extraction destroys semantic information)

Challenges

- High data dimensionality, unbalanced classes
- Process drift (non-stationarity of data due to changing machine state)
- Analysed data is merely a subset of whole process

Data



A subset of 35 electrical measurements from wafer is shown.

Two classes signify "high yield" and "low yield". Ratio of training to test data is 3:1 (in chronological order). Independent test set is vital for feature selection [4].

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	Method	Features	Samples	"Low Yield"
Data Set 1	Feature sel.	61	3000	57%
	Test	61	1000	31%
Data Set 2	Feature sel.	85	1000	48%
	Test	85	313	57%

Methods

Yield prediction

FAM is a suitable classifier for wafer data

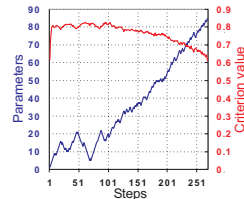


Extract Fuzzy-Rules:
"IF parameter A in [0.0476,0.524]
AND ...
THEN "Low Yield"

Few Rules ← Many Rules
Easy Interpretation ← High Accuracy

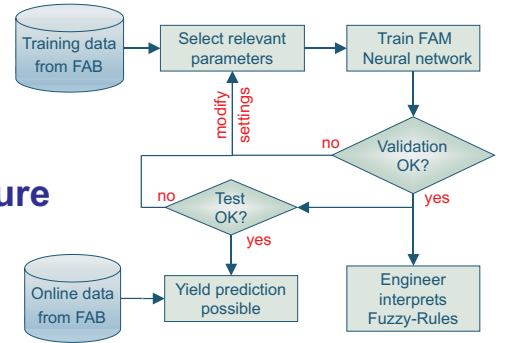
Feature Selection

Sequential Forward Selection (SFS)
Sequential Forward Floating Selection (SFFS) [3]

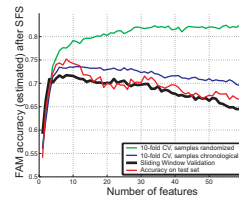


Criterion functions used:
Fuzzy ARTMAP (FAM)
k-NN (k=5, Euclidean distance)
Mahalanobis distance (M-dist)

System Architecture



Error Estimation



Problem

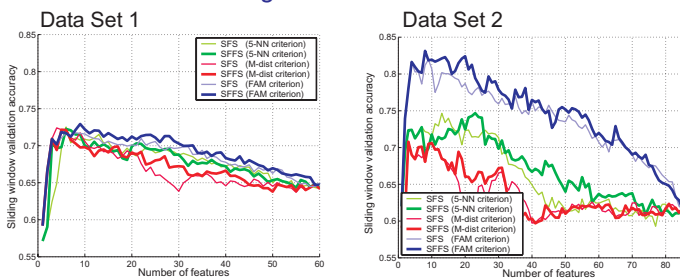
Cross-validation is overoptimistic due to low within-lot variation

Solution

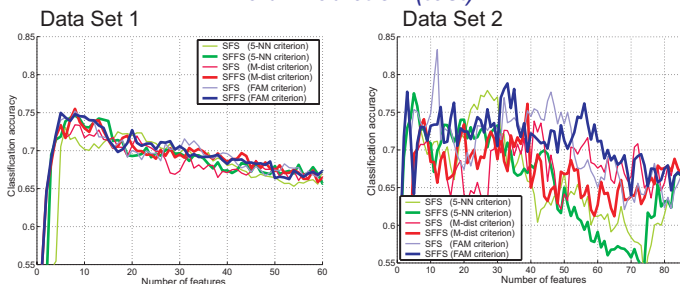
- Do not randomise data during CV
Keep chronological order of data
- Sliding window validation (SWV)
SWV imitates online case - data from a few lots is used to train the FAM, chronologically succeeding data is used for the test

Results

Sliding Window Validation



Yield Prediction (test)



A feature subset of size 5-15 gives best yield prediction for Data Set 1. The trend is not as clear for Data Set 2. As expected, the FAM criterion function delivers the best results.

Discussion

- SFFS is not superior to SFS when predicting wafer yield
- A small feature subset can model a production problem well
- Yield prediction improves after feature selection

A real production problem was solved by combining

- Feature selection
- Fuzzy Rules extracted from FAM
- Engineer's problem solving competence

Further Challenges

- Visualisation of Fuzzy Rules
- More datasets needed to prove generality of results and allow online yield prediction

[1] G.A. Carpenter and S. Grossberg. Fuzzy ARTMAP: A neural network architecture for incremental supervised learning of analog multidimensional maps. IEEE Transactions on Neural Networks, 1992.
[2] Isabelle Guyon and André Elisseeff. An introduction to variable and feature selection. Journal of Machine Learning Research, 2003.
[3] P. Pudil, F.J. Ferri, J. Novovicova, and J.V. Kittler. Floating search methods for feature selection with nonmonotonic criterion functions. In ICPR94, pages 279-283, 1994.
[4] Juha Reunanen. Overfitting in making comparisons between variable selection methods. Journal of Machine Learning Research, 2003.

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